

Estrada™

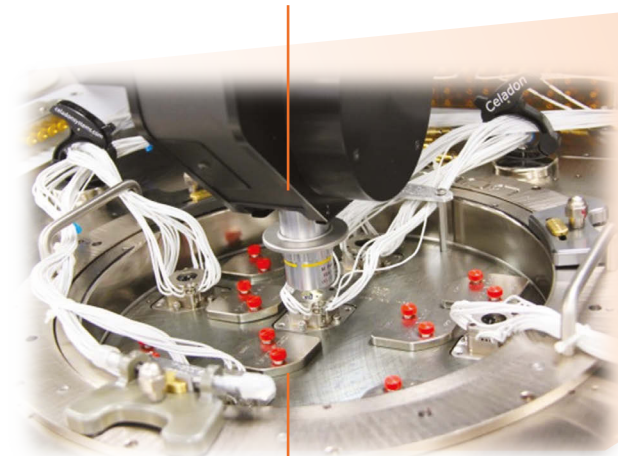
FEL: Semi-automated test cell for full-wafer, multisite WLR

CM300xi semi-automated probe station

- Active vibration isolation system and High-Temperature Stability (HTS) platen for long-term contact stability at elevated temperatures
- MicroChamber® shielding for low-noise environment
- Camera-based automatic XYZ and theta wafer alignment to simplify loading
- Locking roll-out stage for safe and convenient handling of 300 mm and smaller/partial wafers

eVue™ microscope and large-area motorized bridge

- Downward-looking camera for in-situ alignment at temperature
- Programmable movement from site to site across entire wafer for fast multi-site alignment and verification



Full-wafer, multi-site Celadon probe card

- Up to 17 test sites for multiple dies in parallel
- Up to 1x32 or 2x16 probes per site for multiple DUTs in parallel within each die
- High-temperature design for longevity and data integrity
- CTE-matched design with individual test site position adjustments to accommodate thermal changes
- Patch panels to flexibly re-map SMU signals to probes

Conductor test executive software

- Automated testing at multiple touchdown points for high throughput with low operator effort
- Flexible test sequence programming with same or different tests in parallel and at each touchdown to produce large sample sizes and evaluate a broad range of test conditions with a single start

Velox™ prober control software

- Intuitive GUI for efficient system utilization
- Software joystick for precise, sub-micron positioning
- CellView for improved sub-die navigation

Symphony™ reliability test system

- Compact system with high channel count
- Scalability and reconfigurability to adapt to changing needs
- Same SMUs and software as 1164 package-level system for combined analysis
- Zeus full-featured, intuitive GUI for reliability test software for flexibility and quick setup



Constant voltage TDDb and SILC packages

- Up to 192 DUTs in parallel for high throughput
- Multiple Application Module options to test a variety of technologies up to ±150 V / 350 mA per DUT
- True parallel measurements with fast sampling to capture soft breakdown in detail and minimize SILC relaxation

HCI and conventional BTI packages

- Up to 48 DUTs in parallel for high throughput
- Multiple Application Module options to test a variety of technologies up to ±150 V / 100 mA per DUT
- Accurate, parallel stress/measure sources for minimized relaxation and high-quality data

20°C - 300°C thermal system

- Broad temperature range for test condition flexibility
- Ultra-flat chuck for stable and repeatable measurements and consistent probe depth at multiple sites across wafer

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